

Title (en)

MICROWAVE PROCESSING APPARATUS

Title (de)

MIKROWELLENBEHANDLUNGSVORRICHTUNG

Title (fr)

APPAREIL DE TRAITEMENT PAR MICRO-ONDES

Publication

EP 3852496 A4 20211201 (EN)

Application

EP 19860278 A 20190906

Priority

- JP 2018168391 A 20180910
- JP 2019035168 W 20190906

Abstract (en)

[origin: EP3852496A1] A microwave treatment apparatus includes: a treatment chamber configured to accommodate a heating target; a microwave supply configured to supply microwaves to the treatment chamber; and a resonator unit having a resonance frequency in a frequency band of microwaves. The resonator unit includes a plurality of patch resonators disposed such that at least three patch resonators are arranged along an orientation of a polarization plane generated on a metal wall constituting the treatment chamber. According to an aspect, a standing wave distribution in the treatment chamber, that is, a microwave energy distribution, can be controlled.

IPC 8 full level

H05B 6/70 (2006.01); **H05B 6/64** (2006.01); **H05B 6/68** (2006.01)

CPC (source: EP)

H05B 6/70 (2013.01)

Citation (search report)

- [XI] US 2012175363 A1 20120712 - RON AMICHAI [IL], et al
- [XAI] FR 2775552 A1 19990903 - STANDARD PRODUCTS IND [FR]
- [Y] WO 2017081855 A1 20170518 - PANASONIC CORP [JP]
- [Y] WO 2017141826 A1 20170824 - PANASONIC CORP [JP]
- [A] WO 2015133081 A1 20150911 - PANASONIC CORP [JP]
- [E] EP 3651552 A1 20200513 - PANASONIC CORP [JP]

Designated contracting state (EPC)

AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

Designated extension state (EPC)

BA ME

DOCDB simple family (publication)

EP 3852496 A1 20210721; EP 3852496 A4 20211201; CN 111183708 A 20200519; CN 111183708 B 20220614; JP 7380221 B2 20231115;
JP WO2020054608 A1 20210830; WO 2020054608 A1 20200319

DOCDB simple family (application)

EP 19860278 A 20190906; CN 201980003759 A 20190906; JP 2019035168 W 20190906; JP 2019569855 A 20190906